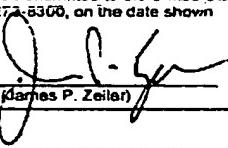


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**EXPEDITED PROCEDURE  
Art unit 2822**

Docket No.: 29936/39764  
(PATENT)

I hereby certify that this paper is being facsimile transmitted to the United States Patent and Trademark Office, Fax No. (571) 272-8300, on the date shown

Dated: December 18, 2006 Signature:   
(Charles P. Zeiler)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Cha Deok Dong

Application No.: 10/720,457

Confirmation No.: 4077

Filed: November 24, 2003

Art Unit: 2822

For: Method for Forming Device Isolation Film in  
Semiconductor Device

Examiner: M. M. Trinh

**AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116**

*Do not enter  
m  
12/27/06*  
MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the official action dated October 18, 2006, finally rejecting claims 1-14, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 3 of this paper.